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Substitute for form 1449A/PTO INFORMATION DISCLOSURE STATEMENT BY APPLICANT (use as many sheets as necessary)				Complete if Known	
		Application Number	10/789,319		
		Filing Date	02/27/2004		
		First Named Inventor	Xu et al.		
		Group Art Unit	1712		
		Examiner Name	Zimmer, Marc S.		
		Attorney Docket Number	P121-63-03		
Sheet	8	of	25		

U.S. PATENT DOCUMENTS						
Examiner Initials*	Cite No. ¹	U.S. Patent Document		Name of Patentee or Applicant of Cited Document	Date of Publication of Cited Document MM-DD-YYYY	Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear
		Number	Kind Code ² (if known)			
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	A240	6,677,252	B2	Marsh	01-13-2004	
	A241	6,696,157	B1	David et al.	02-24-2004	
	A242	6,696,220	B2	Bailey et al.	02-24-2004	
	A243	6,703,190	B2	Ellan et al.	03-09-2004	
	A244	6,703,256	B1	Bloomstein	05-04-2004	
	A245	6,713,238	B1	Chou et al.	03-30-2004	
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Examiner Signature	mjs. 7/1/05				Date Considered	6/6/05

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¹Unique citation designation number. ²See attached Kinds of U.S. Patent Documents. ³Enter Office that issued the document, by the two-letter code (WIPO Standard ST.3). ⁴For Japanese patent documents, the indication of the year of the reign of the Emperor must precede the serial number of the patent document. ⁵Kind of document by the appropriate symbols as indicated on the document under WIPO Standard ST. 16 if possible. ⁶Applicant is to place a check mark here if English language Translation is attached.

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ELECTRONIC INFORMATION DISCLOSURE STATEMENT

Electronic Version v18

Stylesheet Version v18.0

Title of
Invention

COMPOSITION FOR AN ETCHING MASK COMPRISING A
SILICON-CONTAINING MATERIAL

Application Number : 10/789319



Confirmation Number: 9202

First Named Applicant: Frank Xu

Attorney Docket Number: P121-63-03

Art Unit: 1712

Examiner: Marc S. Zimmer

Search string: (6468642 or 5542978 or 5837314 or 6565776 or 6503914 or 6649272 or 6204343
or 4614667 or 3810874 or 6737489 or 6721529 or 6664306 or 6790905 or 6544594
or 6774183 or 6830819 or 6802870 or 5389696).pn

US Patent Documents

Note: Applicant is not required to submit a paper copy of cited US Patent Documents

init	Cite.No.	Patent No.	Date	Patentee	Kind	Class	Subclass
1/1	1	6468642	2002-10-22	Bray et al.	B1		
	2	5542978	1996-08-06	Kindt-Larsen et al.			
	3	5837314	1998-11-17	Beaton et al.			
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	5	6503914	2003-01-07	Benish et al.	B1		
	6	6649272	2003-11-18	Moore et al.	B2		
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	9	3810874	1974-05-14	Mitsch et al.			
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	11	6721529	2004-04-13	Chen et al.	B2		
	12	6664306	2003-12-16	Gaddam et al.	B2		
	13	6790905	2004-09-14	Fitzgerald et al.	B2		
	14	6544594	2003-04-08	Linford et al.	B2		
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Signature

Marc Zimmer

6/13/05

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INFORMATION DISCLOSURE STATEMENT BY APPLICANT (use as many sheets as necessary)		Application Number	10/789,319
		Filing Date	02/27/2004
		First Named Inventor	Xu et al.
		Group Art Unit	1712
		Examiner Name	Zimmer, Marc S.
Sheet	21	of	25
		Attorney Docket Number	P121-63-03

OTHER PRIOR ART - NON PATENT LITERATURE DOCUMENTS			
Examiner Initials*	Cita No.	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume/issue number(s), publisher, city and/or country where published.	T ²
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Examiner Signature	<i>Marc Zimmer</i>	Date Considered	6/6/05
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		First Named Inventor	Xu et al.
		Group Art Unit	1712
		Examiner Name	Zimmer, Marc S.
Sheet 18 of 25	Attorney Docket Number	P121-63-03	

OTHER PRIOR ART - NON PATENT LITERATURE DOCUMENTS			
Examiner Initials*	Cita No.	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published.	T ²
mg	A422	KOSEKI, "Design and Accuracy Evaluation of High-Speed and High Precision Parallel Mechanism.", Proc. Of IEEE, January 1, 1998, Int. Conf. on Robotics & Automation, pp. 1340-1345.	
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Examiner Signature	<i>Marc Zimmer</i>	Date Considered	<i>6/1/05</i>
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PTO/SB-33A (3-03)

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